

JVX 7300 Thin Film Metrology Tools

- Non-contacting, Non-destructive Technology
- Fully Automated Measurements and Analysis
- High-volume Fab Design
- Low Cost of Ownership
- Angstrom-level Accuracy and Resolution
- Layer Thickness, Density, and Roughness (XRR)
- High resolution XRD (HRXRD)
- SiGe, Si:C, SOI: Composition, Thickness, Strain, Relaxation,

Item	Qty	Part Number	Item	Description
	1	JVX7300 300 mm	Model	JVX7300 platform for 300mm wafers. Performs direct measurements on patterned wafer features
	1	N/A	Ballroom Configuration	Ballroom Configuration
* HRXRD Channel				
	1		HRXRDAAdv Channel	HRXRD Advanced channel. monitoring Strain, relaxation, SiGe composition% & thickness for blanket or product wafers, including full SOI support.
* XRR Channel				
	1		XRR Vega 2nd Channel	XRR Channel (2nd channel) - source and optics provide <= 10nm (FWHM) spot. Automatically controls spot size for scribe line measurements for small pad size 600um*45um.
* XRF channel				
	1	**This item will be upgraded in the field in Q4 2012	XRF Channel for 7300	XRF Channel (3rd channel) , SiLe detector, dry cooled, small spot - 22µm (FWHM) spot
* Software Options				
	1		JV HRXRD SW offline	HRXRD modeling software for offline use. Simulation / refinement. One license per unit.
	1		JVXrrs Offline	XRR modeling software for offline use. Simulation / refinement. One license per unit.
* Handler & Automation Options				
	1		Mini Environment for Dual Load Port	Airflow ME for Dual 300mm load ports, including Light curtain , 2 RF Tag Reader, 2 DeviceNet for RFID Reader, Ionizer Kit and Internal light kit
	2	AS00361	Load Port	FOUP load port (300mm)
	1	AC00003	300mm Automation - SECS/GEM package	Full 300mm Automation package from Cimatrix. Includes material state information in addition to recipe and data automation.
	1	AS00241	E84 Automation	Factory-installed E84 Automation kit for OHT. Supports two load ports.
* Hardware Options				
	1		Chamber Laminar Flow	
	1		Brackets	Earthquake brackets kit